



0321.68095

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Yeshaiahu Fainman  
Serial No.: 10/521,425  
Conf. No.: 9057  
Filed: 3/22/2005  
For: HOLOGRAPHICALLY DEFINED  
SURFACE MASK ETCHING  
METHOD AND ETCHED OPTICAL  
STRUCTURES  
Art Unit: 2814  
Examiner: Rao, Shrinivas H.

*I hereby certify that this paper is being deposited with the United States Postal Service as FIRST-CLASS mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this date.*

8/17/07 Al F. R  
Date Registration No. 43,874  
F-CLASS.WCM  
Appr. February 20, 1998 Attorney for  
Applicant(s)

AMENDMENT A

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the Office Action mailed May 7, 2007.